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the component ratio "x" of A1 is in a range of $0.3 \le x \le 1.0$, so that said semiconductor laser light emitting device is configured as an index guide type semiconductor laser light emitting device.

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9. (Once amended) A semiconductor laser light emitting device comprising:

a stacked film composed of a stack of group III nitride semiconductor films each containing at least one kind selected from aluminum, gallium, indium, and boron;

wherein,

an upper portion of said stacked film is formed into a ridge-like stripe, to form a current injection region;

a current injection width Wst of said current injection region is in a range of 1 μ m \leq Wst \leq 3 μ m;

a current non-injection region formed on both sides of said ridge-like stripe;

at least part of said current non-injection region is made from a material expressed by a chemical formula $A1_xGa_{1-x}N$ ($0 \le x \le 1.0$); and

the component ratio "x" of A1 is in a range of 0.15 < x < 0.30, so that said semiconductor laser light emitting device is configured as a weak index type pulsation semiconductor laser light emitting device.



17. (Once amended)

A semiconductor laser light emitting device comprising:

a stacked film composed of a stack of group III nitride semiconductor films each containing at least one kind selected from aluminum, gallium, indium, and boron;